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Our Ref. No.: 051876P232

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application for:

)
Won-Ick Jang

)
Serial No. 09/753,065

)
Filed: December 29, 2000

)
For: **STICTION-FREE
MICROSTRUCTURE RELEASING
METHOD FOR FABRICATING
MEMS DEVICE**

)
Examiner: Lan Vinh

)
Art Group: 1765

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BOX NON-FEE
AMENDMENTS
Commissioner for Patents
Washington, D.C. 20231

RESPONSE TO OFFICE ACTION

Dear Commissioner:

In connection with the Office Action mailed August 12, 2002, regarding the above-referenced application, Applicants respectfully request consideration of the following amendments and remarks below.